## Part III - Microscopy

**Chapter 6: Fundamentals** 

Resolution Limits, Modulation Transfer Function, Lens Aberrations, Comparison Optical and Electron Microscopy, 3D Imaging

**Chapter 7: X-Ray and Electron Microscopy** 

**Chapter 8: Contrast and Modulation Transfer Function** 

**Chapter 9: Advanced Techniques** 

Confocal Scanning Microscopy, 3D Optical Imaging, Super-resolution using PALM, STORM, STED, NSOM

## Chapter 6

## **Fundamentals of Optical Microscopy**

Instrumentation, Resolution Limits, Aberrations, Practical Resolution: Optical Microscopy versus TEM





## Contents - Chapter 6: Fundamentals of Optical Microscopy

6.2 How to Perform Spatial Imaging with High Resolution ?	3
6.3 Scanning Microscopy	5
6.4 Imaging Microscopy	7
6.5 Resolution Limits of Imaging Microscopy	11
6.6 Resolution Limit due to Diffraction	<b>12</b> 
<ul> <li>6.7 Modulation Transfer Function and Resolution in Fourier Space.</li> <li>6.7.1 Example: Periodic Line Grating</li> <li>6.7.2 Fourier Decomposition of the Sample Contrast</li> <li>6.7.3 Modulation Transfer Function</li> <li>6.7.4 Image Formation using the Modulation Transfer Function</li> <li>6.7.5 Experimental Determination of the Modulation Transfer Function</li> </ul>	22 
6.8 Axial Resolution and Depth of Field	33
6.9 Z-Series: A Method to Overcome the DOF Limitation	36
6.10 Resolution Limits due to Lens Aberrations 6.10.1 Spherical Aberration. 6.10.2 Chromatic Aberration. 6.10.3 Astigmatism.	<b></b>
6.11 How to Maximize the Microscope Resolution ? 6.11.1 Reducing Diffraction Broadening 6.11.2 Correction of Lens Aberrations	<b>44</b> 45 47
6.12 Application to Light Microscopy	54
6.13 Summary	60

## **6.1 Introduction**

- <u>Microscopy</u> = High resolution 2D or 3D real space <u>spatial imaging</u>, i.e., <u>mapping</u> of materials properties on a <u>magnified scale</u>.
- This yields the *microscopic landscape* of properties such as morphology, mass density, chemical composition, reflectivity, absorption, luminescence efficiency, or any other property, depending on which type of response signal and probe sample-interaction is recorded as imaging signal. Most common: Imaging of structure, morphology or composition of materials.
- Microscopic imaging is possible in principle for all material characterization methods described in the previous chapter. However, the achievable spatial resolution can be quite different due to the different used probes.

#### In this chapter:

- The <u>principle approaches</u> and methods of microscopy are introduced and the <u>image formation</u> <u>processes</u> described,
- » <u>**Resolution limits**</u> and conditions for best resolution are derived for optical imaging microscopy and transmission electron microscopy,



#### Optical microscopy (HM, PCM):

**Visible light**: Resolution down to 200 nm ( $\approx \lambda/2$ ).

- **Electron Microscopy:** (TEM, SEM) **Electron beams**: Small wavelengths  $\lambda \ll A$ TEM: Resolution of atom rows, limited by optics, SEM: Resolution limited by interaction volume,
- Field ion microscopy: (FIM, FEM) Imaging using electrons or ions: Direct imaging of single atoms at surface steps, Limited to tip-shaped samples with radius<100 nm,
- Scanning proximal probe microscopy:

Proximal probes with very small tip radius and localized (near-field) interaction Atomic resolution possible for STM & AFM.

#### Type of probe determines:

(a) Resolution, (b) probe-sample interaction (c) information type, (d) required technical instrumentation.



10<sup>4</sup>

LATERAL SCALE

#### Chapter VI: Fundamentals of Optical Microscopy

Å

## 6.2 How to Perform Spatial Imaging with High Resolution ?

#### A. <u>Scanning microscopy</u> = Local excitation + non-local detection

- ⇒ Excitation of a small sample volume by a tightly *focused beam probe* produced by *demagnifying* optics.
- ➡ Global detection of the response signal from the sample by an integrating detector
- ⇒ 2D images created by raster scanning the probe over the sample surface

**Examples:** Scanning electron microscopy(SEM), scanning optical (SOM), scanning probe (SPM), scanning x-ray microscopy (SXRM), .....



#### B. <u>Imaging microscopy</u> = Non-local excitation + Local detection.

- ⇒ Excitation of a large sample volume but detection only the signal from a small volume that is projected by <u>magnifying optics</u> onto the detector.
- ⇒ 2D images created usually by *parallel detection* of many individual spots using a two dimensional pixel detector such as a photoplate, human eye, CCD camera, channel plate, etc., for which one pixel corresponds to the signal from one small sample spot.

**Examples:** Transmission electron microscopy (TEM), optical imaging microscopy (OM) ...

#### C. Local excitation and local detection: Combination of both.

Example: Confocal scanning optical microscopy, ....

Chapter VI: Fundamentals of Optical Microscopy

#### **Imaging Microscopy**

#### **Scanning Microscopy**



Magnifying optics required for image formation, magnification determined by focal length



⇒ Demagnifying optics for probe formation, Magnification set by scan size

#### Note: The same type of variants exist for electron and x-ray microscopy

## 6.3 Scanning Microscopy

In scanning microscopy, an image is created by raster scanning a small probe that locally interacts/excites the sample and the detection of the global response signal I(t) as a function of time, where at a given time *t* the probe is at a different spot (x,y)= f(t) on the sample.

⇒ Each image point is recorded sequentially at a different time linked to a certain spot position !



<u>Magnification</u> = simply the ratio between display and scan size:  $M = w_{display} / w_{scan}$ The smallest useful scan size is limited by the probe size, i.e.,  $w_{scan} > w_{probe}$ .

**Resolution** is determined only by the probe size as well as interaction/excitation volume. The probe size depends on the quality of the demagnifying optics and wavelength of the probe, and the interaction volume on the probe energy and interaction strength.

Chapter VI: Fundamentals of Optical Microscopy

#### **Characteristic Features of Scanning Microscopy**

- On the second second
- © Thus, applicable to *wide range of techniques* because no imaging optics are required.
- © Easy to combine with *spectroscopic* techniques. Thus, probing of many properties possible.
- Ultimate resolution = determined by the probe size and the interaction volume. For beam probes, the probe size is *limited by diffraction* and the *lens aberrations* of the focusing optics. The *excitation volume* depends on the probe parameters. In confocal fluorescenece microscopy (STED) it can be narrowed below the diffraction limit using *non-linear optical effects*.
- Sequential point-by-point recording is slow and limits the signal integration times per pixel.
- Overall, only a *virtual sample image* is obtained that represents measured signal versus (x,y).
   The image must be displayed on a monitor screen, photo plate, printer, etc. .

<u>Variants</u>: Scanning Electron Microscope (SEM), Scanning Tunneling (STM) and Scanning Force Microscope (AFM), Scanning Near Field (SNOM) and Scanning Confocal Optical Microscope, ...



## 6.4 Imaging Microscopy

Local detection is achieved by creating an *enlarged image* of each sample point using *magnifying optics* of lenses or curved mirrors. The enlarged image is viewed or recorded using a 2D detector.



<u>Magnification</u>: M = B / G is determined by the lens equation, i.e., object and image distances b/g

At any time, **each point of the image** = signal collected from <u>one point</u> of the sample!

#### Magnification of a two lens optical microscope

Given by lens strength  $f_i$  and tube length t



⇒ The tube length *t* of optical microscopes is usually fixed (standardized to t = 160 mm). Thus, different objective lenses with different  $f_i$  have to be used to change the magnification.

#### **Basic features of imaging microscopy:**

- ★ <u>Resolution</u>: Due to diffraction and lens imperfections, the image of each point of the object is smeared out on the detector. Thus, below a certain distance *r*, two object points can no longer be resolved. The resolution depends on the imaging wavelength λ and the quality of the optical imaging system but it is *fundamentally limited* to *r* > ½ λ.
- ★ <u>Useful magnification</u>: Although by using strong lenses with small *f* and a large tube length *t* the magnification M<sub>mag</sub> ≈ t / f can be made be arbitrarily large, due to the resolution limit the "useful" magnification is <u>finite</u>



#### Instrumentation

For the different probes very different kinds of instrumentation, i.e., beam sources, optical elements, detectors, environmental conditions, etc. is required but the basic opitical system is identical.

#### **Example: Optical Microscope** versus Transmission Electron Microscope



<u>Different</u> (1) Beam sources: Light verus electrons, (2) Lenses: Glass versus magnetic/ electrostatic lenses, <u>elements</u>: (3) Environment: Air versus vacuum column, (4) Photon versus electron detectors, (5) High voltage

#### Key features of imaging microscopy

- ☺ A <u>real physical image</u> of the sample is formed within the image plane.
- Thus, all sample points are simultaneously imaged at once at the same time: This enables <u>real time imaging</u> of the whole sample at high speeds to reveal fast dynamical changes occurring within samples as a function of time.
- © Long integration times per point are possible that yield high signal-to-noise ratios.
- ⊗ The resolution is *fundamentally limited* by diffraction (~wavelength).

**Variants of imaging microscopy:** Light microscopy (OM) using visible/IR/UV light, transmission electron microscopy (TEM), low energy reflection electron microscopy (LEEM), photo emission electron microscopy (PEEM), field ion microscopy (FIM), etc.



#### Examples: Left: Optical microscopy with different contrast. Right: TEM image

Different variants of imaging microscopy are distinguished according to (i) the kind of waves used for illumination and (ii) how the contrast is formed in the image.

Chapter VI: Fundamentals of Optical Microscopy

## 6.5 Resolution Limits of Imaging Microscopy

Ultimately, the lateral resolution of any microscopy system is limited by two factors:

- 1. Diffraction effects due to the finite entrance aperture of the optical system
  - = <u>fundamental</u> & ultimate <u>resolution limit</u> ( = Abbe resolution limit,1873)
- 2. <u>Image distortions/smearing</u> caused by *lens imperfections* (aberrations) = "<u>practical</u>" <u>resolution limit</u> (always > diffraction limit)
- ⇒ Both effects limit the resolution *independently* of the magnification of the optical system.

For <u>beam scanning microscopy</u>, both effects lead to a **broadening of the probe spot size** on the sample, with a certain minimal diameter that cannot be further reduced.

For *imaging microscopy* this leads to a *broadening of the image* of each object point, i.e., the smallest resolvable distance between to points is limited.

In sum, the total <u>effective resolution</u>  $r_{eff}$  is given by the square root summation:



## 6.6 Resolution Limit due to Diffraction (see, e.g., E. Hecht: "Optics")

In any optical system, *diffraction* occur at all *apertures* confining the optical beam.

The corresponding diffraction patterns can be derived using the <u>Huygens principle</u>, where the electric field and thus, the intensity at a point *P* away from the aperture is calculated by *summation* over spherical waves emitted with wave vector  $k=2\pi/\lambda$  from every point within the aperture of area *A*.



Chapter VI: Fundamentals of Optical Microscopy

Resulting far-field intensity distribution  $I(\theta)$  for a single slit

$$I(\theta) = c \cdot \varepsilon_0 \left\langle E^2(\theta, t) \right\rangle_t = c \cdot \varepsilon_0 \left\langle \sin^2(\omega t) \right\rangle_t \cdot 2E_0^2 \sin^2(\frac{1}{2} \cdot kb \sin \theta) / (kb \sin \theta)^2$$

$$I(\theta) = \left\langle E(t)^2 \right\rangle = I_0 \cdot \sin^2 \beta / \beta^2 \quad \text{with} \quad \beta = \frac{\pi \cdot b \cdot \sin \theta}{\lambda} \quad , \quad \theta = \text{diffraction angle}$$

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#### **Basic Properties:**

- **1. Central intensity maximum**  $I_0$  with series of side minma and maxima.  $I_0 = c \cdot \varepsilon_0 \cdot E_0^2 = c \cdot \varepsilon_0 \cdot (\varepsilon/R)^2$
- **2.** <u>Intensity minima</u> occur at:  $\sin \beta = 0 \rightarrow \beta = m^{-}\pi \rightarrow \frac{\sin \theta}{\sin \theta} = \lambda^{-}m/b$ , m = 1, 2, 3...
- **3.** <u>Phase difference</u> of out-most beams for these minima:

 $\Delta \phi = m \cdot \lambda$  *note* :  $\lambda = \lambda_o / n$ (wavelength in medium)

- 4. <u>Broadening of the image</u> = Separation between the central maximum and the first side minimum:  $sin \theta_1 = \lambda/b$
- 5. Stronger diffraction, i.e., larger angles and broader image the smaller the slit width b.

#### 6.6.2 Diffraction by a Circular Aperture (Airy disk)

Diffraction pattern of a circular aperture (=Airy disk) with diameter D and radius  $R_0$ : Derived in a similar way by *summation over all spherical waves* emitted from the disk area





 Central intensity maximum with concentric satellite rings
 "Airy intensity distribution"

#### The Airy intensity distribution

is described by first order Bessel function  $J_1$ 

$$I(\theta) = I_0 \cdot \left[\frac{2 \cdot J_1(kR\sin\theta)}{kR\sin\theta}\right]^2$$

 $\theta$  = diffraction angle,  $k = 2\pi n / \lambda$  = wave vector, R = aperture radius



#### **Properties of the Airy intensity distribution:**

Intensity-Minima are given by zeros of the Bessel function  $J_1(x) = 0$  at x = 3.83, 7.01, 10.17, ...

 $\Rightarrow x = 3.83, 7.01, \dots = \sin\theta^{-2}\pi R/\lambda \rightarrow \theta_{\min}(rad) = m_i^{+}\lambda/D$  with  $m_i = 1.22, 2.23, 3.24, \dots$ 



i.e., the intensity minima are more closely spaced, i.e., the diffraction broadening reduced !

#### 6.6.3 Application: Minimal Spot Size of a Laser Beam

The minial spot size of a quasi parallel laser beam focused onto a sample is limited by the diffraction at the lens aperture, i.e., by the finite lens diameter or finite beam diameter (=beam waist).



The diffraction angle of the 1<sup>st</sup> Airy disk cause by the diffraction is given by  $\theta_{\min,1} = 1.22 \cdot \lambda/Dn$ , which is appears at a point P<sub>1</sub> at a distance *x* away from the optical axis with  $x = f \tan \theta$ .

When the lens diameter D is large,  $\theta_{\min}$  is small and thus,  $x = f \tan \theta \approx f \cdot \theta$ .

As a result, the diameter of the Airy disk or beam spot size is  $d_{spot} = f \ 1.22^{\circ} \lambda/D$ ,

*i.e.*,  $d_{spot} = 1.22 \cdot \lambda f/D$ 

where the parameter *f*/*D* is called "*f*" number of the lens

For a Gaussian beam, the laser does not fill

the aperture uniformly and thus, the focal spot is slightl increased to

Example:  $\lambda = 680$ nm, D = 5 mm, f = 5mm »  $d_{spot} = 1.9 \mu$ m

Chapter VI: Fundamentals of Optical Microscopy

В

n

 $4/\pi^{-}\lambda f/D$ 

 $d_{spot} =$ 

#### 6.6.4 Broadening in a Magnified Image: Point Spread Function

For a microscope, the resolution is generally described by the so-called *point spread function* that is defined as the *image of an ideal point source* produced by an optical system.

Its shape characterizes the performance of a microscope system and *includes all broadening factors* caused by *diffraction* at the entrance aperture <u>as well as</u> by <u>lens aberrations</u>.



For a *perfect* diffraction-limited optical system without any lens aberrations, the lateral point

spread function, i.e., radial intensity distribution I(x) of a point source is the *Airy diffraction pattern*, which within the parallaxial approximation (small angles) is:

$$I_{Airy}(x) = I_0 \cdot \left[\frac{2 \cdot J_1(2\pi \cdot n \sin \alpha \cdot x / M\lambda)}{2\pi \cdot n \sin \alpha \cdot x / M\lambda}\right]^2$$

where again  $J_1$  is the first order Bessel function,  $\alpha$  is the aperture angle, *n* the refractive index of the medium between the object and lens, *M* the magnification and  $\lambda$  the wavelength of the light.

#### Measurement of the point spread function

The point spread function of an optical system can be directly *measured* by recording the image of a point source, for example of a single fluorescent molecule or a small nanocrystal or quantum dot.



The width of the central maximum in the image, i.e., the *radius of the first dark ring* determines the ultimate microscope resolution and for a perfect optical diffraction limited system is given by:



Chapter VI: Fundamentals of Optical Microscopy

#### 6.6.4 Diffraction Limit of the Lateral Resolution (Abbe Limit)

In a microscope, the finite diameter of the objective lens acts as a finite size circular aperture that creates an Airy diffraction pattern in the image plane for every point of the object.

#### **1. Resolution Criteria**

When two object points are very close to each other, the point spread function (Airy patterns) of their images overlap so that eventually the two points can no longer be resolved.

#### (a) Rayleigh Criterion

Rayleigh

Two point sources can be just resolved when the central **maximum** of the diffraction pattern of one point coincides with the **minimum** of the neighbouring point.



(b) <u>Sparrow Criterion (= Ultimate resolution limit)</u>

Two point sources can be just resolved when there starts to exists an intensity dip between the image of the points.

 $\mathbf{r} = \mathbf{r}_{1st}$  Airy disk

 $r = 0.61 \lambda / n \sin \alpha$ 

#### 2. Abbe resolution limit using the Rayleigh criterion

In a **microscope**, the diameter *D* of the objective is finite and thus acts as a finite size circular aperture that creates an Airy diffraction pattern in the image plane for each point of the object.

As shown on the previous slides, for an object point *O* at the optical axis, the diffraction angle  $\theta_{\min}$  at which the 1<sup>st</sup> Airy intensity minimum is formed in the image is given by  $\theta_{\min} = 1.22 \cdot \lambda/D$  (see Figure below) where  $\lambda = \lambda_{vac}/n$  is the wavelength of light in the medium between the lens and the objective with refractive index *n* that changes the wavelength in the medium.



Tracing back this position I' to the object plane, this image point corresponds to an object point at position O' that according to the Raleigh criterion can still be resolved.

As seen in the figure, point O' is separated vertically from point O by the distance:  $r = \tan \theta_{\min} \cdot l_{obj}$  where  $l_{obj} \sim f$  is its distance from the objective lens.

Since for  $\lambda \ll D$ ,  $\tan \theta_{\min} \approx \theta_{\min}$  it follows that  $r_{\min} = \theta_{\min} \cdot l_{obj} = 1.22 \lambda/n \cdot l_{obj} / D_{len} = 0.61 \lambda/n \cdot l_{obj} / R_{lens}$ .

Because  $l_{obj}/R = \sin \alpha$  » the <u>diffraction limited resolution</u> turns out to be:

 $r_{min} = 0.61 \lambda / n \sin \alpha$ 

#### **3. Resolution and Numerical Aperture**

The diffraction limited resolution	$r_{dif} = 0.61 \lambda / n \sin \alpha$	Wavelength (nm)	Resolution (nm)
<i>increases</i> with (i) decreasing wavelength λ, and (ii) decreasing acceptance angle α The denominator		360 – 450 nm (violet)	190 – 250 nm
		450 – 500 nm (blue)	250 – 300 nm
		500 – 570 nm (green)	300 – 350 nm
<b>NA</b> = $n \sin \alpha$ is called "Nume	rical Aperture"	620 – 750 nm (red)	380 – 460 nm

It combines the aperture angle  $\alpha$  of the entrance lens and the refractive index *n* of the medium between sample and lens and thus, characterizes the properties of a given optical lens system.

The numerical aperture NA can be increased by (a) increasing the diameter of the objective lens and/or (b) decreasing the focal length *f* of the lens as shown by the figures below:

 $\Rightarrow$  High NA = small working distance WD » small f-number » high magnification [M ~ t / f]

$$\Rightarrow$$
 But: For *n* =1, sin $\alpha$  is limited to < 1  $\Rightarrow$  NA < 1.



### 6.7.1 Example: Periodic Line Grating

For a 2*b* periodic line grating with line width *b*, the angles  $\varphi_i$  of the diffraction maxima are given by:

 $\sin \varphi_i = i^{-} \lambda / (2 n b)$  with i ... diffraction order, n ... refractive index,  $\lambda$  ... wavelength

If the grating is imaged with an objective lens with a capture angle  $\alpha$ , only diffracted beams with  $\phi_i < \alpha$  can contribute to the image formation.



#### **Resolution Criterion:**

The grating can only be resolved if at least the 1<sup>st</sup> order diffracted beams are still collected by the lens ( $\varphi_1 \leq \alpha$ ).

**<u>Condition</u>**: sin  $\varphi_1 = \lambda / (2 n b_{\min}) =! \sin \alpha$ 

$$\rightarrow \quad \mathbf{R} = b_{\min} = 0.5 \cdot \lambda / (n \cdot \sin \alpha)$$

or 
$$R = 0.5 \cdot \lambda / NA$$

with NA=  $(n \sin \alpha)$ (numerical aperture of the lens)

- ⇒ Thus, the objective acts as a low pass filter in diffraction space !
- Off-axis illumination increases the resolution because more higher order diffraction maxima go through the objective.

unterschied von  $\Delta f / \cos \alpha - \Delta f$ 

#### 6.7.2 Fourier Decomposition of the Sample Contrast

Any real space object with contrast  $C_s(x,y)$  can be thought to be build up of a sum of sinus and cosine functions of various wavelengths  $\lambda$  or wave vectors  $k = 2\pi/\lambda$  with amplitudes A(k) or  $A(\lambda)$ .

$$C(x,y) = \int_{-\infty-\infty}^{\infty} \int_{-\infty-\infty}^{\infty} A(k_x,k_y) e^{-i(k_x x + k_y y)} dk_x d_y$$

(For periodic functions, the integral can be replaced by a summation:)

$$C(x) = \frac{a_0}{2} + \sum_{n=1}^{\infty} A(n) \sin(k_n x) + B(n) \cos(k_n x) \text{ where } k_n = \frac{2\pi n}{\lambda}$$

An exact 1:1 representation of C(x) requires an *infinite number* of Fourier components.

If in an image formation process, the higher order spatial frequencies are cut off, i.e., A(k)=0 for  $k > k_c$ *i.e.*, only a *finite Fourier series* contributes to the image, the sample contrast  $C_s(x,y)$  is no longer exactly reproduced, i.e.,  $C_{image}(x,y) \neq C_{sample}(x,y)$ . This is what happens in any imaging process !



#### Fourier series representation of the sample contrast

In Fourier space, the **contrast**  $C_s(x, y)$  of a real space object is represented by a summation of plane waves with an infinite number of spatial frequencies  $k = 2\pi/\lambda$  which are weighed by different amplitudes  $A(k_x, k_y)$  (=Fourier components), i.e.,

$$C(x,y) = \int_{-\infty-\infty}^{\infty} \int_{-\infty-\infty}^{\infty} A(k_x,k_y) e^{-i(k_x x + k_y y)} dk_x d_y$$

where  $k_x = 2\pi/\lambda_x$  and  $k_y = 2\pi/\lambda_y$  are the wave vectors in x and y direction inversely proportional to the corresponding **spatial wavelength**  $\lambda_{x,y}$ .  $A(k_x, k_y)$  is the **amplitude** of the plane wave component with wave vector  $(k_x, k_y)$ . Thus:  $C(x, y) = FFT(A(k_x, k_y))$ .

The <u>Fourier amplitudes</u>  $A(k_x, k_y)$  (=contribution of each frequency or wavelength to C(x,y)) can be calculated by the <u>inverse Fourier transformation</u> (iFFT) of the object contrast function C(x,y).

Thus:  $A(k_x, k_y) = iFFT(C(x, y))$ 

$$A(k_x,k_y) = \frac{1}{4\pi^2} \int_{-\infty}^{\infty} \int_{-\infty}^{\infty} C(x,y) e^{+i(k_x x + k_y y)} dx dy$$

From the knowledge of the Fourier amplitudes  $A(k_x, k_y)$  the sample structure C(x, y) can be reconstructed and vice versa.



#### **6.7.3 Modulation Transfer Function**

#### 1. Perfect optical imaging

For a **perfect imaging process**, each spatial frequency contained in the object is <u>perfectly</u> reproduced, i.e.,  $A_{image}(k_x, k_y) = A_{sample}(k_x, k_y)$ .

This means that the sample contrast

 $C(x,y) = FFT(A(k_x,k_y))$  is <u>exactly</u> reproduced in the image without any loss of information

#### 2. Real optical imaging

In a real *imaging system*, different spatial frequencies are reproduced differently well, i.e.,

high spatial frequencies (small period structures) are generally reproduced less well than low spatial frequencies. This means that the amplitudes A(k) of Fourier components with high spatial frequencies contained in the object are reduced by a certain factor in the image.

The ability of a lens system to reproduce different spatial frequencies of the object in the image is characterized by the modulation transfer function MFT(*f*) or MFT(*k*).

#### **Definition of the modulation transfer function:**

$$MTF(k) = \frac{\text{image contrast modulation}}{\text{object contrast modulation}} = \frac{A_{im}(k)}{A_{obj}(k)}$$

at a given spatial frequency k.



For a perfect imaging MTF = 1 at all frequencies, whereas for a real imaging system the MTF decreases with increasing wave vector, i.e., with decreasing periodicities contained in the sample. As a result, there exists a certain **maximum** *cut-off spatial frequency*  $k_c$  above which the MTF is zero, meaning that all high frequency information is eliminated in the image formation.

A lens system acts like a <u>low pass Fourier filter</u> such that the contributions of the higher spatial frequencies in the image are removed.



#### Example for modulation transfer MTF(k) plotted versus spatial frequency $k = 1/\Lambda$

#### Modulation Transfer Function MTF(k) of a Diffraction Limited System

The modulation transfer function is the inverse FFT of the *point spread function* (*=image of a point-like light source*). For a <u>diffracting limited optical system</u> the MTF is given by:

MTF(*k*) =  $2(\phi - \cos\phi \sin\phi)/\pi$  where  $\phi = \cos^{-1}(k \lambda_{illu}/2NA)$ 



- > At *low spatial frequencies*, MTF(k) =  $A_{im} / A_{obj} \sim 1$ . Thus, the image contrast is equal to that of the sample. At *higher frequencies*, MTF decreases and falls to zero at the cut-off frequency  $k_c$ .
- > For a diffraction limited system, the <u>cut off frequency</u>  $k_c$  is given by:  $k_c = f_c = 2.1 \text{ NA} / \lambda$ Thus, the highest spatial frequency is determined by the Sparrow limit.
- The corresponding radius of the first dark concentric ring surrounding the central peak of a point spread function is given by:
- r =0.61 λ / NA
- > Objectives with low NA produce a wider point spread functions and thus, lower resolution.

#### 6.7.4 Image Formation using the Modulation Transfer Function

Once the modulation transfer function MTF(k) is known, the amplitude of the Fourier components of the image, i.e.,  $A_{image}(k_x, k_y)$  can be calculated using:

 $A_{im}(k) = \mathsf{MTF}(k) \cdot A_{obj}(k)$ 

From the known  $A_{image}(k_x, k_y)$ , the **real space image**  $S_{image}(x, y)$  can be calculated by back transformation of  $A_{image}(k_x, k_y)$  into real space:

$$S_{im}(x) = iFFT[A_{im}(k)] = iFFT[MTF(k) \cdot A_{obj}(k)]$$

#### Example: Influence of the modulation transfer function on image formation



The contrast modulation of the object at a spatial frequency k is given by the corresponding **Fourier amplitude**  $A(k_{x,ky})$  of the object contrast C(x,y).

This amplitude is obtained by the Fourier transformation of the object contrast distribution C(x,y) or I(x,y)that represents the real space structure of the object

A <u>perfect optical system</u> with infinitely high resolution would have a modulation transfer function of **MTF = 1** (unity) for *all* spatial frequencies. Only then, it follows that  $I_{image}(x,y) = I_{object}(x,y)$  !!!



The modulation transfer function includes both image broadening effects due to diffraction and Lens imperfections. A lens system without aberrations is termed diffraction limited.

#### **Example: Testpattern for Image Resolution**

"Siemens Star"



#### 6.7.5 Experimental Determination of the Modulation Transfer Function

The modulation transfer function and point spread function of any optical system including a microscope can be *determined* using a point-like light source such as single fluorescing molecules, quantum dots or nanocrystals, or illuminated point like apertures.

#### **Procedures:**

- (a) The intensity distribution of the image of the point source corresponds to the **point spread** function of the microscope.
- (b) The Fourier transform of this intensity profile of the point source image yields the modulation transfer function MTF(k)



Image of the point source

- (c) The MTF can be also *directly measured*: It is the diffraction pattern formed in the *back focal plane* of the objective system.
- (d) The intensity profile of a sharp shadow edge can be also used to determine the MTF function, again by calculating the Fourier transform of the intensity profile in the image.

In general, for an ideal point source the modulation transfer function corresponds to the *diffraction pattern* formed in the *back focal plane* of the objective system, and the point spread function to the intensity distribution in the image plane.

Thus, the MTF and PSF are strictly interrelated by the Fourier transformation.



#### Modulation Transfer Function

#### The modulation transfer function:

- continuously decreases with increasing spatial frequency until it reaches zero at the cut-off frequency k<sub>c</sub> (or f<sub>c</sub>)
- all frequencies higher than k<sub>c</sub> are completely blocked by the optics.
- high performance objectives with large NA have a higher cut-off frequency and higher MFT values at lower frequencies.



## 6.8 Axial Resolution and Depth of Field

The point spread function is actually a **3D** *intensity distribution* in (x,y) as well as z (axial) direction.

#### **Axial intensity distribution:**

$$I_{Airy}(x=0,z) = C \cdot \frac{NA^4}{M^2} \left[ \frac{\sin(\pi NA^2 \cdot z/2n * M^2 \lambda)}{\pi NA^2 \cdot z/2n * M^2 \lambda} \right]^2$$

This means that the image of a point source is not only broadened in the lateral, but also *in the axial direction*, with an axial width (=1<sup>st</sup> zero of l(z)

$$\Delta z_{Airy} = 2n * \cdot M^2 \lambda / NA^2$$

Thus, the *axial resolution*, defined as minimal z-separation of two points that can be discriminated in the microscope when focusing through the object is limited to:

## $\Delta z_{res} = 2n * \lambda / NA^2$

PSF

-100

#### The Rayleigh Criterion for Lateral and Axial Resolution





#### **Depth-of-Field**

Due to the broadening of the PSF in the axial direction an object part that is offset from the ideal focal plane appears broadened in the image plane.

The **Depth-of-field (DOF)** is thus defined as the

vertical distance or sample depth over which a microscopy image appears still sharp.

 $\Rightarrow$  Like the lateral resolution, the DOF is determined by acceptance angle  $\alpha_0$  (*NA*) of the objective lens.



**Derivation of the DOF** using the following resolution criterion:

**Criterion:** DOF = Depth of sample across which the broadening  $\delta(z)$  due to the spreading of the light cone by  $\alpha_0$  is equal to the lateral resolution  $r_{diff}$  in the focal plane, i.e.,  $\delta(z) = r_{diff}$ 

From above figure:  $\delta = d \tan \alpha \quad \& \quad r_{diff} = 0.61 \ \lambda / n \sin \alpha \Rightarrow d = 0.61 \ \lambda / (\tan \alpha n \sin \alpha)$ 

 $\Rightarrow \text{ DOF} = 2^{\cdot}d = 1.22 \lambda^{\cdot} (n^2 - NA^2)^{1/2} / NA^2 \text{ For small } \alpha: \text{ DOF} \approx n^{\cdot} \lambda / NA^2$ 

» Increasing the numerical aperture NA <u>decreases</u> the depth-of-field of the image !





#### **Conclusions**:

- ⇒ For large sample thicknesses or large topography variations, the image is not sharp over the whole microscopy image.
- ⇒ A high lateral resolution and a large DOF cannot be achieved at the same time.
- A large DOF mean a low axial resolution because at large DOF the microscope cannot discriminate between objects located at different z-positions. This ability is called axial resolution, which is important for 3D imaging of the objects in x,y,z direction.

## 6.9 Z-Series: A Method to Overcome the DOF Limitation

To overcome the limit of image sharpness due to the finite DOF, a whole series of images (= "z-stack") can be recorded with incremental vertical shifts of the focal plane.

From each image, the **sharp parts** are selected by an image processing software, and a total *virtual image* is constructed only from the sharp regions for the whole sample series.



#### **Selection criterion**:

The sharpest z-element is that with the highest local contrast modulation, i.e., the element with containing the highest spatial frequencies.

#### **Example: Z-Series for Optical Imaging Microscopy**

When a z-image series is recorded with precisely-controlled z-displacement increments  $\Delta z$ , the x,y coordinates of the sharp parts of the images can be correlated with their location in z-direction. In this way, a *complete 3D sample image* is obtained.



#### **Lateral resolution:** $\Delta x = 0.66 \lambda / NA \sim \lambda / 2$ Vertical resolution: $\Delta z = DOF \sim n^{-} \lambda / NA^{2} \sim \lambda$

Chapter VI: Fundamentals of Optical Microscopy

## 6.10 Resolution Limits due to Lens Aberrations

For imperfect optical systems, the PSF point spread function is additionally broadened.

This is due to the fact that imperfect lenses do not focus all beams exactly on the same image spot in the image. This leads to a smearing of the image and thus, the resolution is decreased.



The resulting effective resolution is described as the RMS sum of

diffraction broadening  $r_{\text{diff}}$  <u>and</u> aberration broadening  $r_{\text{aber}}$ : The overall performance of an ojective lens is then characterized by an <u>effective numerical aperture</u>  $NA_{\text{eff}}$ : which is always smaller than the geometrical numerical aperture !



 $NA_{eff} = n \sin \alpha r_{dif} r_{eff}$ 

There are <u>three main types of lens errors</u> (aberrations) that degrade the spatial resolution: (1) Spherical Aberration, (2) Chromatic Aberration and (3) Astigmatism.

Spherical aberration arises from the spherical shape of optical lenses.

A spherically shaped lens acts differently on central and far off-axis rays:



```
Focal plane
```

#### Example: Calculation of spherical aberration for a simple half-spherical lens

Focal length *f* for a thin spherical lens: 
$$\frac{1}{f} = (n-1)\left(\frac{1}{R_1} - \frac{1}{R_2}\right)$$
. Half-spherical lens:  $\int_0^{\infty} \frac{R}{n-1}$   
(1) Incidence angle  $\gamma$  on curved lens surface:  $\sin \gamma = y/R$ 

(2) <u>Refraction</u> of beam at curved surface (Snell's law):  $\sin \beta = n \cdot \sin \gamma$  » Focusing angle  $\alpha = (\beta - \gamma)$ 

(3) Focal distance of outer rays:  $\tilde{f}(y) = y / \tan \alpha \approx f_0 \left[ 1 - k(y/R)^2 \right]$  for  $\alpha < 10^\circ$ , k = constant

(4) <u>Additional shift</u>  $\Delta$  of origin:  $\Delta(y) = R - x = R(1 - \cos \gamma) \approx 1/2R \cdot (y/R)^2$  for  $\alpha < 10^\circ$ 



Chapter VI: Fundamentals of Optical Microscopy



**Example:** Curvature R = 10 cm, refractive index n = 1.5, corresponding focal length  $f_0 = 20$  cm

Light with different wavelengths or energies are refracted differently by the lens due to the **dispersion**  $n(\lambda)$  of the refractive index of the lens material.

> Broadening of the spot size (spot radius  $r_{chr}$ ) according to

$$\Delta \mathbf{f} \sim \Delta \lambda: \qquad \mathbf{r}_{chr} = C_c \frac{\Delta \lambda}{\lambda} \alpha^m = C_c \frac{\Delta E}{E_0} \alpha^m$$



 $C_c$  ... chromatic aberration constant: ~ dn/d $\lambda$  or ~ dE/d $\lambda$  or ~ df/d $\lambda$ ,  $m \sim 1$ 

Example: Dispersion  $n(\lambda)$  of the refractive index for typical lens

#### **Chromatic aberration**

- ⇒ strongly depends on the material properties
- ⇒ increases with increasing wavelength spread of the used light



#### 6.10.3 Astigmatism

= Non-uniform action of the lens in two orthogonal directions.

#### Main origin:

Asymmetries of the lenses, misalignments of the optical system, electric stray fields due to charging in electron microscopy.

 Broadening of the spot size/radius r<sub>ast</sub> according to

$$r_{ast} = \alpha \Delta f$$



In all, the

⇒ **total effective resolution** is given by:

 $r_{\rm eff} = (r_{\rm dif}^2 + r_{\rm sph}^2 + r_{\rm chr}^2 + r_{\rm ast}^2 + ...)^{1/2}$ 



## 6.11 How to Maximize the Microscope Resolution ?

For <u>any</u> microscope, the **total effective resolution**  $r_{tot}$  is given by the <u>sum</u> of diffraction and aberration broadening according to:

total effective resolution:

$$r_{tot} = \sqrt{r_{dif}^2 + r_{sph}^2 + r_{chr}^2 + r_{ast}^2} = 0.61 \cdot \lambda / NA_{eff}$$

which is characterized by the effective numerical aperture NA<sub>eff</sub>

For highest resolution <u>all</u> terms must be minimized, however: Diffraction broadening and aberration broadening <u>counteract</u> each other !

$$r_{tot} = \sqrt{\left(\frac{0.61\lambda}{n\sin\alpha}\right)^2 + \left(C_{sph}\alpha^3\right)^2 + \left(C_{chr}\frac{\Delta\lambda}{\lambda}\alpha\right)^2 \dots}$$

- Diffraction broadening is proportional to ~1 / sin  $\alpha$
- Aberration broadening is proportional to  $\sim \alpha^n$
- $\Rightarrow$  With increasing aperture  $\alpha$ , diffraction broadening decreases but lens aberration increase.

#### **Consequences:**

- The resolution cannot be simply increased by increasing the lens diameter: Instead a compromise in  $\alpha$  must be made that minimizes the <u>sum</u> of all broadening factors.
- This means that there exists a certain <u>optimum aperture angle</u>  $\alpha_{opt}$  where the *highest resolution* is achieved. This is particularly important for electron microscopy, where the lens aberrations are very large and dominate the resolution.

#### 6.11.1 Reducing Diffraction Broadening

Numerical apertures  $NA = n \cdot \sin \alpha$ : Means that  $\alpha$  as well as *n* should be maximized

#### (a) Increasing the aperture angle

α = tan(*D*/2f)

requires lenses with large diameter *D* and/or smaller focal length *f*.

- For microscopes with fixed tube length and with fixed objective diameter D, α can be increased only by decreasing the focal length f of the objective,
- $\Rightarrow \text{ Reducing } f \text{ means also reducing the} \\ \text{working distance } w \sim f$

**Consequence:** Because at the same time the magnification M = t/f, increasing *f* simultaneously increases the magnification:

- ⇒ High NA (and high resolution) is obtained only at high magnification !
- ⇒ A high NA also gives a high brightness of the image, which is proportional to  $\sqrt{(NA)}$



$$r_{diff} = 0.61 \cdot \lambda / n \sin \alpha$$

Resolution & Numerical Aperture for $\lambda = 550$ m (green)			
Magnification	N.A.	Resolution (µm)	
4x	0.10	1.375	
10x	0.25	0.61	
20x	0.40	0.37	
40x	0.65	0.29	
60x	0.75	0.29	
N.A. = Numerical Aperture			

#### (b) Increasing the refractive index n: Immersion Microscopy

Introducing a *liquid medium* with refractive index n > 1 between the sample and objective reduces the diffraction angles and thus, increases  $\alpha_{eff}$ .

This is called *immersion microscopy*.

Numerical apertures NA > 1 can be obtained, which reduces diffraction broadening and improves resolution

 $r_{diff} = 0.61 \cdot \lambda / n \sin \alpha$ 



*air:* n = 1, water: n = 1.33, glycerine: n = 1.47synthetic oils: n = 1.51, Bromonaphthalene: n = 1.659, Methylene iodide: n = 1.74,



## 6.11.2 Correction of Lens Aberrations $r_{eff} = \sqrt{r_{diff}^2 + (r_{aber}^2)} = 0.61 \cdot \lambda / NA_{eff}$

⇒ To achieve a diffraction limited resolution, all lens errors must be corrected !

<u>Non-perfect lens system</u>: Performance defined by *effective numerical aperture*  $NA_{eff} < n \sin \alpha$ . This value is *smaller* than  $n \sin \alpha$  and accounts for additional broadenings caused by lens aberrations.

- $\Rightarrow$  Objectives with better corrections yield higher *effective* NA<sub>eff</sub> values close to NA<sub>ideal</sub> =  $n \sin \alpha$
- ⇒ Combination of several lenses in one objective allows to compensate of most lens aberrations.
- (i) Spherical aberration correction: Cause: Spherical curvature of lenses results in stronger bending of outer rays towards the optical axis. Strong effect for "thick" lenses



# Solution #1: Use of several lenses with <u>smaller curvature</u> and smaller aberration Solution #2: Use of <u>asymmetric lenses</u> with two different curvatures on each side to minimize spherical aberration





Solution #3: Combination of positive (convex) and negative (concave) lenses with *positive* and negative spherical aberration constants (dublets and triplets)





#### **Solution #4:** Use of more expensive *nonspherical lenses*

#### (ii) Correction of chromatic aberration

Cause:

Wavelength dependence, i.e., dispersion of the refractive index  $n(\lambda)$ 

#### **Solution:**

Lens *doublets* or *triplets* of convex and concave lenses consisting of glass materials with different dispersion (crown, flint glasses and fluorspar).





#### (iii) Correction of astigmatism

<u>Cause:</u> Asymmetric lenses or misaligned/unparallel optical elements <u>Solution</u>: Improved lens symmetry, precise alignment.

Apochromat

#### (iv) Curvature of field-of-view

For spherical lenses, the image is not focused on a plane but rather on a curved surface.

Cause: Curvature of lens surfaces.

**Solution:** Correction by additional lens elements.



(v) Coma = smearing of outer part of image

**<u>Cause</u>**: Inclined beams have different focal position for outer beams through the lens.

**Solution:** Correction by additional lens elements.



## 6.12 Application to Light Microscopy

In optical microscopy, visible (or near-infrared) light is used for imaging of the sample.

Wavelength: 
$$\lambda[nm] = c/\upsilon = \frac{1240}{E[e]}$$

Energy:

$$E[eV] = h \cdot \upsilon = 1240/\lambda[nm]$$



**Resolution limits:** Since for VIS & NIR optical systems, effective aberration corrections exist that nearly fully eliminate aberration broadening, *diffraction* is the main remaining *limitation* for the spatial *resolution* of VIS & NIR microscopy.

 $\Rightarrow \quad \text{The best resolution is about } \frac{1}{2} \lambda \text{ of the} \\ \text{illumination wavelength } \lambda \text{ using aberration} \\ \text{corrected objectives with high NA } \sim 1 \\ \end{array}$ 

 $r_{res} = r_{diff} = 0.61 \lambda / NA$ 

⇒ Note: Recently, sub  $\lambda/2$  resolution scanning fluorescence microscopy has been developed.

Wavelength (nm)	Resolution (nm)
360 – 450 nm (violet)	190 – 250 nm
450 – 500 nm (blue)	250 – 300 nm
500 – 570 nm (green)	300 – 350 nm
620 – 750 nm (red)	380 – 460 nm

Achromats: Objectives corrected for axial chromatic aberration at two wavelengths (486 nm blue and 656 nm red) and corrected for spherical aberration in the color green (546 nm; see table).

#### **Fluorites** or semic-apochromats:

Additional lenses for spherical corrections at two wavelengths.

#### Apochromats: Best corrected objectives,

correction of spherical aberrations for wide a wavelength region.

#### **Objective Correction for Optical Aberration**

Objective Type	Spherical Aberration	Chromatic Aberration	Field Curvature
Achromat	1 Color	2 Colors	No
Plan Achromat	1 Color	2 Colors	Yes
Fluorite	2-3 Colors	2-3 Colors	No
Plan Fluorite	3-4 Colors	2-4 Colors	Yes
Plan Apochromat	3-4 Colors	4-5 Colors	Yes

see: <u>www.micro.magnet.fsu.edu</u>





Plan: Lenses with field of view curvature correction are termed with additional "plan" prefix.

#### **Specifications of Objective Lenses**

- Type of Objective (Degree of correction)
- Magnification (number)
- Numerical Aperture
- Tube length (mm)
- Cover Glass correction (thickness)





#### Resolution and Numerical Aperture for $\lambda = 550$ nm (green)

Objective Type						
	Plan A	Achromat	Pla	n Fluorite	Ар	Plan ochromat
Magnification	n.a. <sup>R</sup>	esolution (µm)	N.A.	Resolution (µm)	N.A.	Resolution (µm)
4x	0.10	2.75	0.13	2.12	0.20	1.375
10x	0.25	1.10	0.30	0.92	0.45	0.61
20x	0.40	0.69	0.50	0.55	0.75	0.37
40x	0.65	0.42	0.75	0.37	0.95	0.29
60x	0.75	0.37	0.85	0.32	0.95	0.29
N.A. = Numerical Aperture						

**Violet:**  $\lambda$  = 420nm (25% improvement) www.micro.magnet.fsu.edu

#### » Objectives with better corrections yield significantly higher resolution !





» Distorted image without cover

#### **Comparison of Image Quality: Achrochromat**



#### » Sharp only in the center of the image due to coma and field-of-view curvature

#### Planapochromat



#### » Sharp over the whole image with best resolution

## 6.13 Summary

- Two main approaches for microscopy exist: Scanning and imaging microscopy. These either consist of local excitation and non-local detector (scanning microscopy), or non-local excitation and local detection (imaging microscopy).
- In scanning microscopy, the resolution is limited by the spot size and interaction volume.
- In imaging microscopy, the <u>resolution</u> is limited by two factors:

(a) Diffraction at the objective aperture, which yields:

(b) Lens aberrations, introducing broadening

due to spherical & chromatic aberrations

Other aberration effects include coma and field of view curvature.

The **total effective resolution** is thus given by:

- Due to efficient aberrations corrections, the resolution in optical microscopy is mainly diffraction limited. The highest resolution is achieved for *high numerical apertures NA = n sinα* and *short wavelength* λ imaging systems. Further increase in resolution can be achieved by immersion techniques using liquids to increase the refractive index.
- ★ The <u>depth-of-focus</u> decreases with increasing numerical aperture: DOF ≈  $n^{-}\lambda / NA^{2}$ By recording *z*-stacks (focus through series), 3D images can be obtained.

ds:  

$$r_{diff} = 0.61 \lambda / n \sin \alpha$$

$$r_{sph} = C_s \alpha^n \quad n \sim 3, C_s \sim f$$

$$r_{chr} = C_c dn/n \alpha^n \quad n \sim 1, C_c \sim f$$

 $r_{eff} = (r_{dif}^2 + r_{aber}^2)^{1/2}$ 

Chapter VI: Fundamentals of Optical Microscopy

#### **Alternative Derivation of the Microscope Resolution (Abbe Diffraction Limit)**

Since in a microscope, the sample objects do not emit parallel beams but strongly divergent beams (see figure below), the resolution limit has to be derived differently compared to a telescope.

**Derivation according to figure below:** Two points O and O' in the object are separated by distance *r* and appear at the points at I and I' in the image plane. Each image point is broadened by the diffraction at the microscope aperture *D*, i.e., by the point spread Airy function.



**Rayleigh resolution condition:** The points O' and O can be just resolved when the first side minimum of the Airy function of O' in the image coincides with the intensity maximum of O, which is assumed to be located on the optical axis, meaning that also *I* is exactly on the optical axis.

- ⇒ The 1<sup>st</sup> minimum of the Airy function of O' is given when the optical path difference  $\Delta w$  between the outmost rays is equal to:
- ⇒ On the other hand the path difference  $\Delta w$ between outer rays from O' to I is given as:  $\Delta \phi_1 = \underline{O'A I} - \underline{O'B I} = \Delta_1 - \Delta_2 = 2 r \sin \alpha$

Combining yields the (Raleigh Criterion)

**Diffraction Limited Resolution** 
$$r_{min} = 0.61 \lambda / n \sin \alpha$$

 $\Delta \phi_1 = 1.22 \ n \lambda$ 

#### Angular resolution of a *telescope* for far distant objects

 $\alpha_{min}$  = 1.22  $\lambda$  / D





circular aperture with diameter D

= minimum angle of resolution of a telescope with a

Chapter VI: Fundamentals of Optical Microscopy

minimum:  $\theta_1 = 1.22 \lambda / D$ 

**Resolving power:** 



# Lens resolution with laser light (Gaussian beams)

- Laser beam diameter is effective lens diameter: D = 2w
  - Fourier transform of Gaussian is Gaussian

	Standard lens	Gaussian
Aperture size	D	2w
Focal spot size	$1.22 f \lambda / D$	$w_0 = (4/\pi) f \lambda / 2w = 1.27 f \lambda / 2w$
Depth of focus	$1.22 \lambda (2f/D)^2$	$z = 1.27 \ \lambda \ (2f/2w)^2$



#### (b) Planchromat



#### » Sharp over most of the image

#### Microscopic techniques are distinguished according to different criteria

- (a) *How magnification* is achieved and the images are recorded:
  - » Optical imaging microscopy (such as light microscopy, TEM, PEEM, ...) Principle: Wide area (non-local) illumination / local (= spatially resolved) detection
  - » Scanning microscopy (such as scanning optical microscopy, SEM, SPM, …) Principle: Local excitation / wide area (= non-local) detection
  - » Ray magnification microscopy (field electron & field ion microscopy, ...) Principle: Self-luminous emitting sample / spatially resolved detection.
- (b) <u>What kind of probes</u> are used for the image recording process (see Chapter 2) » Light, X-rays, electrons, ions, neutrons, scanning probes, .....
- (c) *What kind of contrast* mechanism is employed:

Examples: Absorption-, phase-, mass-, density-, thickness-, diffraction contrast, etc. .
 Imaging modes: Bight-field microscopy, dark field microscopy, interference contrast and phase contrast microscopy, etc. .. (see subsequent chapters)

- (d) <u>What is the dimensionality</u> of the obtained information (2+1)D, (2+2)D, 3D ... Plan-view imaging, cross-sectional imaging, depth profiling, 3D tomography
- (e) <u>What is the information depth</u>: Surface microscopy, transmission (bulk) microscopy, ...